

ABSTRACT OF THE DISCLOSURE

The present invention provides a cantilever which enables a further improvement of a surface resolution capability of a scanning capacitance microscope (SCM) with regard to a cantilever employed for the SCM, as compared with a case of employing a conventional cantilever. As the cantilever applied to the SCM according to the present invention, that cantilever has a probe part 1 scanning a sample and an electrode part 2 supporting that probe part 1. Moreover, that probe part 1 includes an insulator 1a having a square pyramidal tip and a conductive wiring 1b placed only on one surface of that insulator 1a having the square pyramidal tip.